


LIST OF REFERENCES CITED BY APPLICANT <i>(Use several sheets if necessary)</i>					ATTY. DOCKET NO.:		APPLICATION NO.:	
					4717-10100		10/784,040	
					APPLICANT:			
					Eric NEYRET et al.			
					FILING DATE:		GROUP:	
					February 20, 2004		2825	
U.S. PATENT DOCUMENTS								
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
ABM	AA	6,150,696	11/2000	Iwamatsu et al.	257	347		
	AB							
	AC							
	AD							
	AE							
	AF							
	AG							
	AI							
FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
ABM	AJ	EP 1 158 581	11/2001	Europe	—	—	X	
ABM	AK	JP 7161948 (w/English Abstract)	6/1995	Japan	—	—	X	
ABM	AL	JP2000299451 (w/English Abstract)	10/2000	Japan	—	—	X	
ABM	AM	WO 01/15218 A1	11/2001	PCT	—	—	X	
ABM	AN	WO 03/005434 A2	1/2003	PCT	—	—	X	
	AO							
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)								
ABM	AP	Jean-Pierre Colinge, "Silicon-On-Insulator Technology: Materials to VSLI", 2nd Edition" by, published by "Kluwer Academic Publishers", at pages 50 and 51." 1997						
	AQ							
EXAMINER					DATE CONSIDERED			
					9-16-2004			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								